


<b>Search Notes</b>  	<b>Application/Control No.</b>  10667368	<b>Applicant(s)/Patent Under Reexamination</b>  NOGUCHI, TAKAFUMI
	<b>Examiner</b>  Choi, Jacob Y	<b>Art Unit</b>  2885

SEARCHED			
Class	Subclass	Date	Examiner
362	459, 545, 6, 8, 446, 470, 505, 506, 259, 231	10/20/2005	JC

SEARCH NOTES		
Search Notes	Date	Examiner
Class/Subclass & Text Search Conducted by Examiner (including class 359)	10/20/2005	JC
Updated Search Conducted by Examiner	8/29/2006	JC
Updated Search Conducted by Examiner	2/14/2007	JC
STIC Search was performed by M. Mims (e.g., diffracting grating range)	02/6/2007	JC
Updated Search Conducted by Examiner	8/22/2007	JC
Updated Search Conducted by Examiner	3/14/2008	JC

INTERFERENCE SEARCH			
Class	Subclass	Date	Examiner